

Studies and Optimization of Field Emission from Si Nanowires on Microtubes

Philipp Buchner¹⁺, Lena Fuchshuber¹, Matthias Hausladen¹, Michael Bachmann²
and Rupert Schreiner¹

¹Faculty of Applied Natural Sciences and Cultural Studies, OTH Regensburg, D-93053
Regensburg, Germany

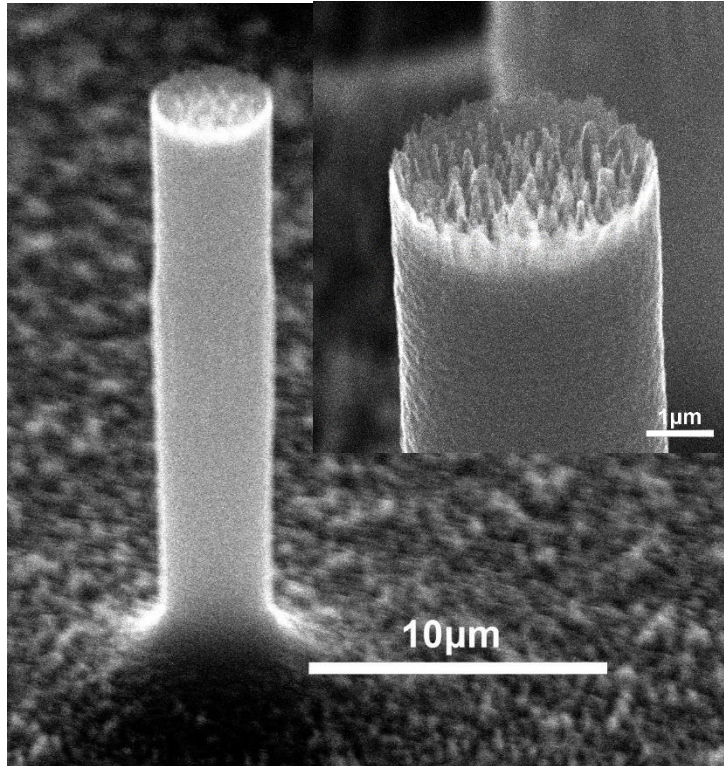
²Ketek GmbH, D-82737 Munich, Germany

⁺philipp.buchner@oth-regensburg.de

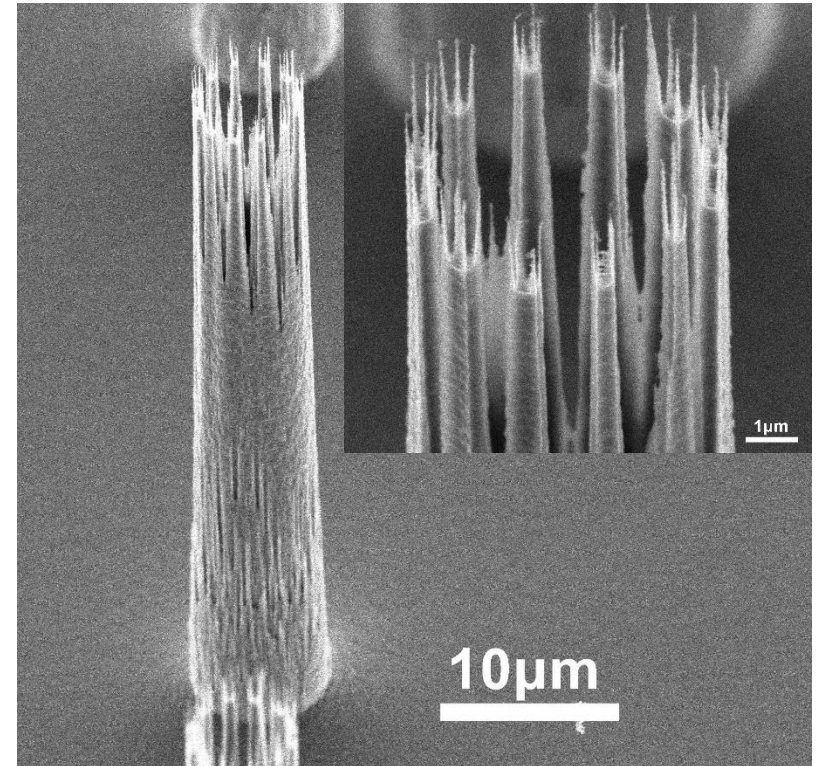
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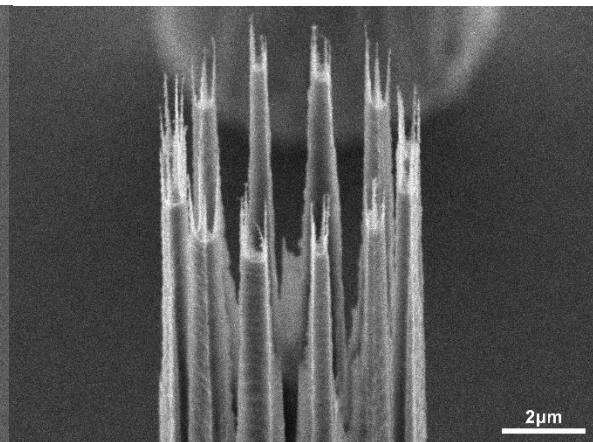
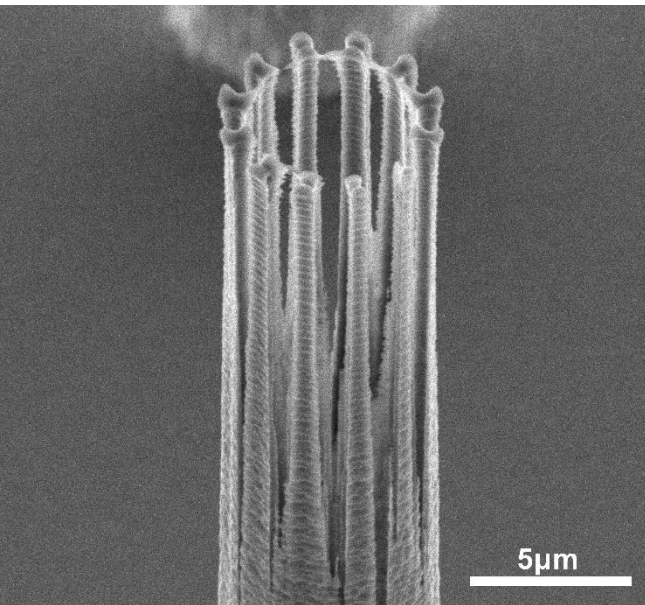
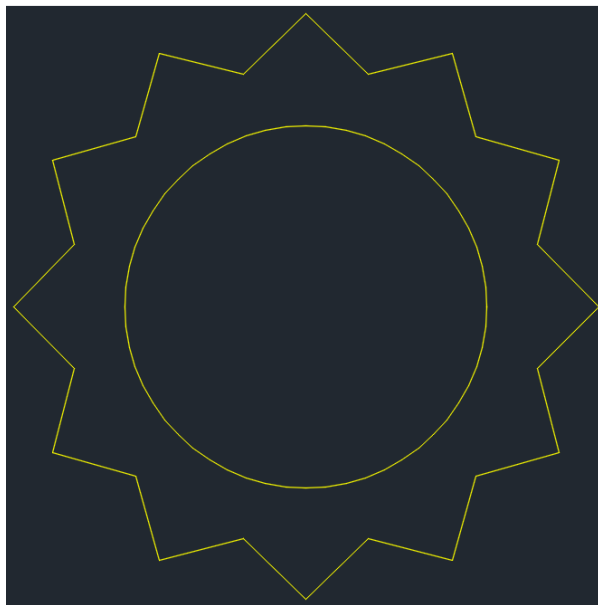
- Reference and samples
- Manufacturing
- Measurement
- Comparison of reference and new samples
- Longtime performance
- Degradation
- Conclusion

b-Si reference



new geometry



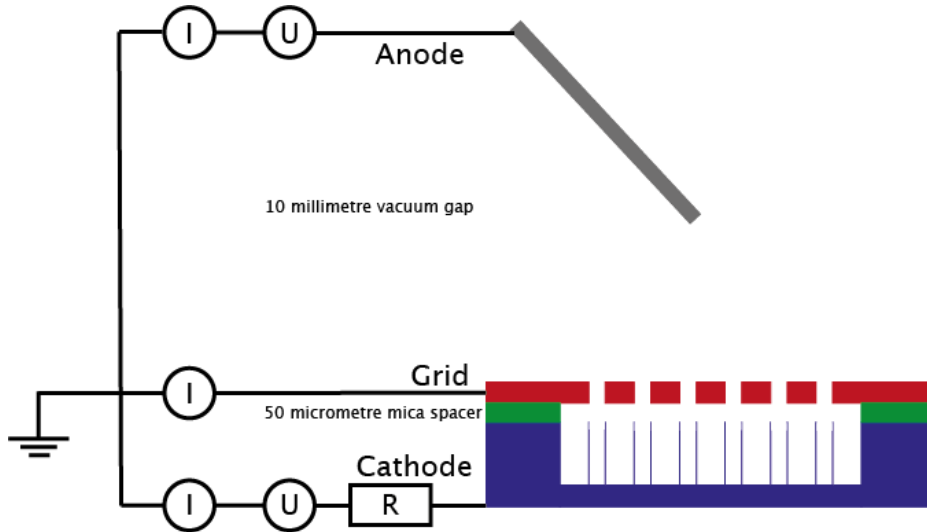


Emitter structured by a four step process:

- generating an irregular photoresist ring
- anisotropically etching the silicon
- removing the photoresist
- repeating the etching step

Two types of silicon used:

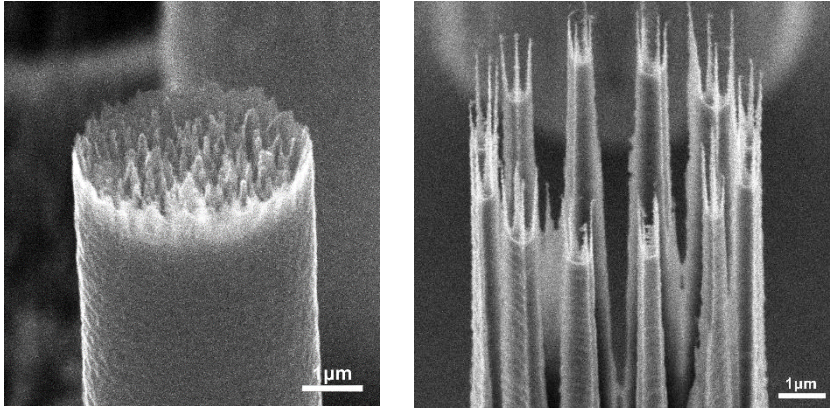
- n-Type (Ph), $\langle 100 \rangle$, 1-10 Ωcm
- n-Type (Ph), $\langle 100 \rangle$, $\langle 0.005 \Omega\text{cm} \rangle$



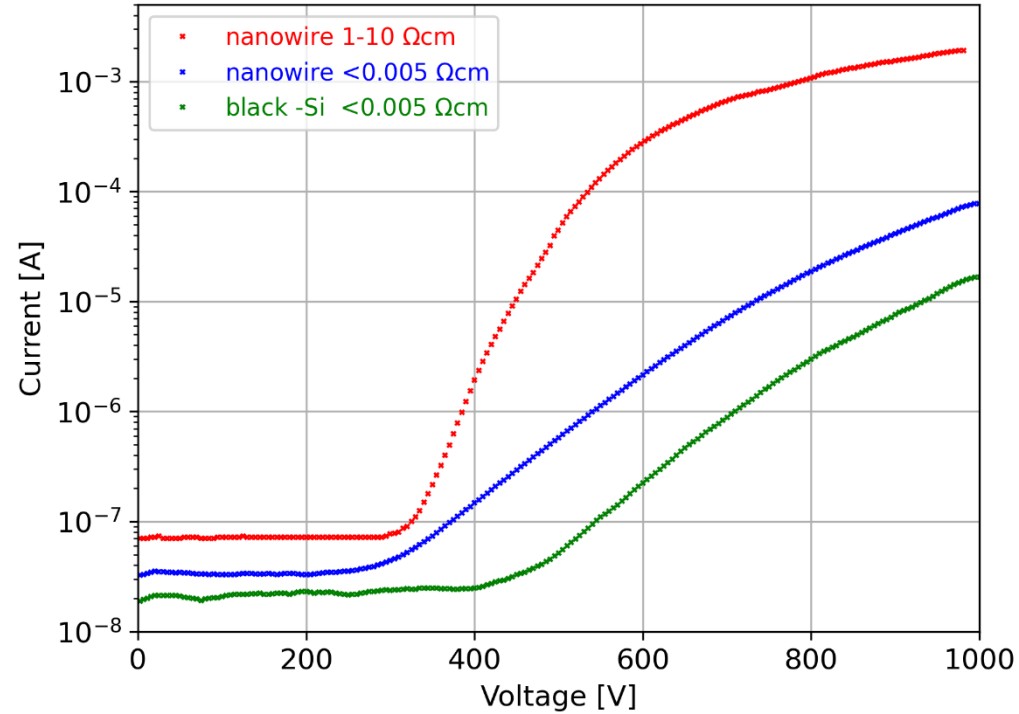
- Measured at a pressure of 10^{-9} hPa
- Shortcheck before and after characterisation
- Measured in 100V increments from 400V to 1000V
- Anode voltage 1000V
- For each voltage the sample was activated for one hour
- For each voltage three up- and downsweeps in 5V steps
→ Further explanation on next slide
- UI-curves generated by averaging the sweeps

- Shortcheck before and after measurement by reversing polarity between cathode and extraction grid
- If a reverse current is measured before or after the measurement the sample is rejected
- One hour of burn in and activation time before the characteristics are recorded
- Each characteristic is repeated three times
- UI-Plots are generated by averaging 6 datapoint for each voltage value (Upsweep and downsweep with three repetitions)
- Once a extraction voltage of 1kV is reached this step is repeated at least for times to establish data on longtime performance (highlighted green)

Comment	Repeats	U_A	U_C
Short Check	1	1kV	0...-100...0...+100...0V
Activation	1	1kV	400V (1h)
Characterisation	3	1kV	0...400...0V (5V steps)
Activation	1	1kV	500V (1h)
Characterisation	3	1kV	0...500...0V (5V steps)
Activation	1	1kV	600V (1h)
Characterisation	3	1kV	0...600...0V (5V steps)
Activation	1	1kV	700V (1h)
Characterisation	3	1kV	0...700...0V (5V steps)
Activation	1	1kV	800V (1h)
Characterisation	3	1kV	0...800...0V (5V steps)
Activation	1	1kV	900V (1h)
Characterisation	3	1kV	0...900...0V (5V steps)
Activation	1	1kV	1000V (1h)
Characterisation	3	1kV	0...1000...0V (5V steps)
Short Check	1	1kV	0...-100...0...+100...0V

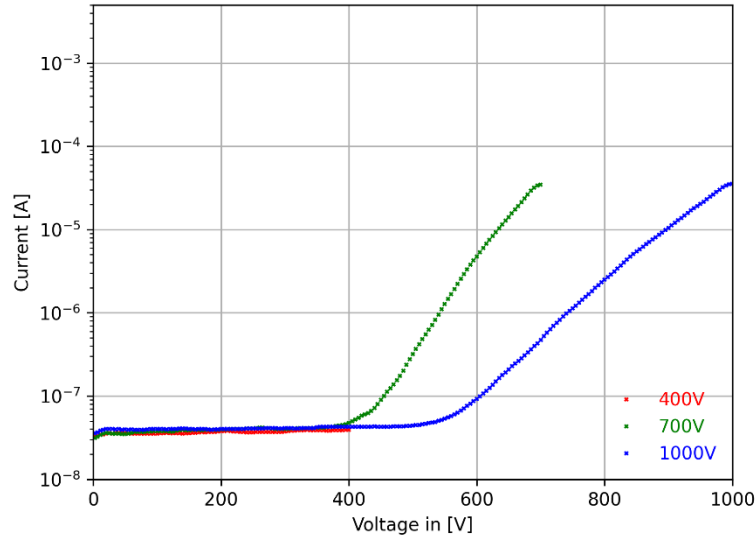


- Nanowire emitters start emitting at lower voltage due to lower shielding and higher field enhancement
- Changing the doping leads to even greater emission current



b-Si reference

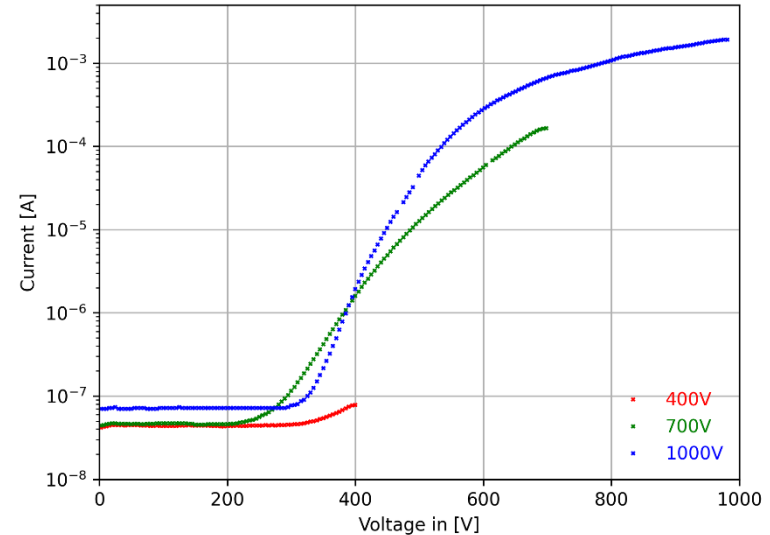
Characteristic Activation



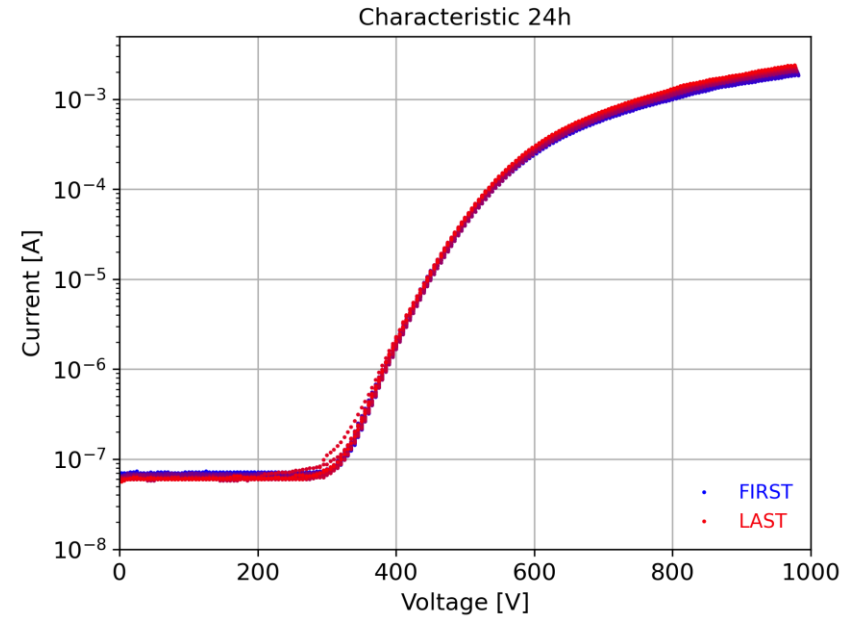
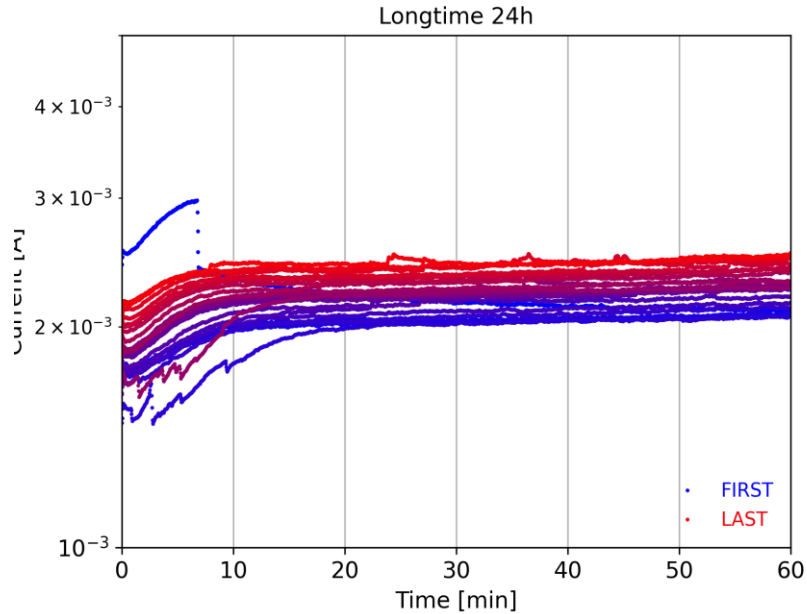
- Reference sample shows no emission current at 400V
- For higher voltages the onset Voltage rises significant due to degradation

new geometry

Characteristic Activation

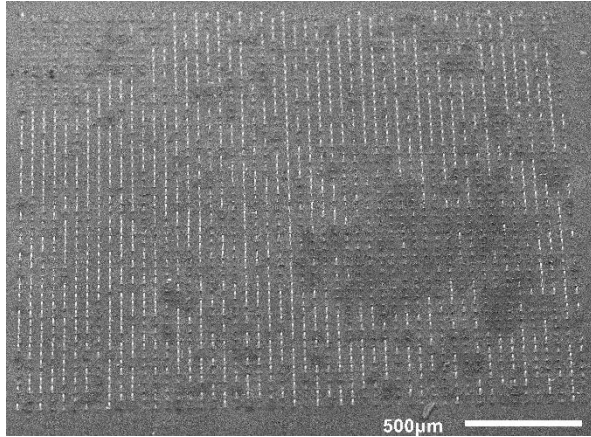


- Reference sample shows emission already at 400V
- For higher voltages the onset Voltage does not rise
→ no or lower degradation

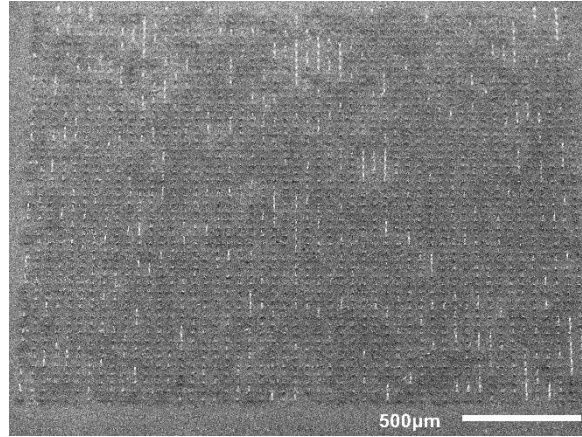


- 24h longtime measurements at 1000V for the new emitter show no degradation

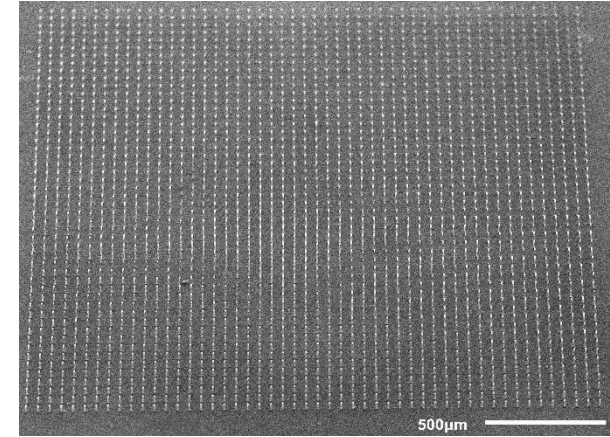
b-Si reference



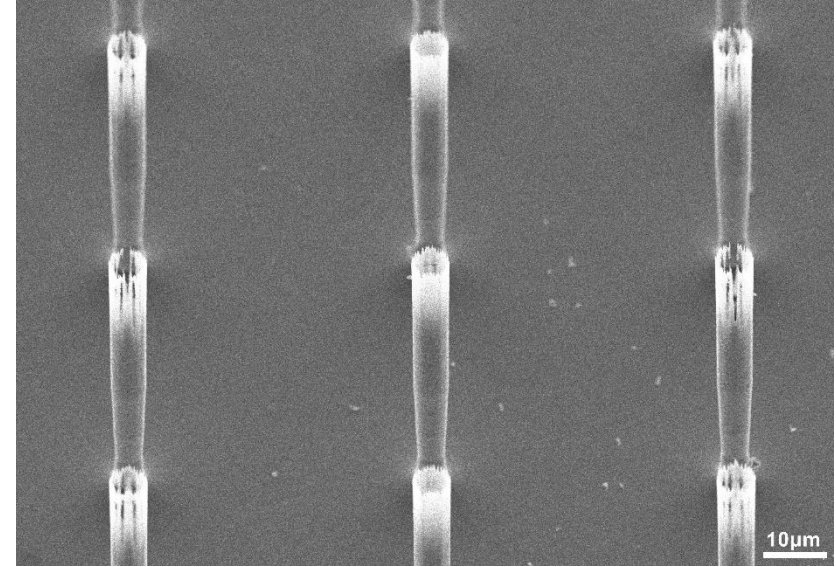
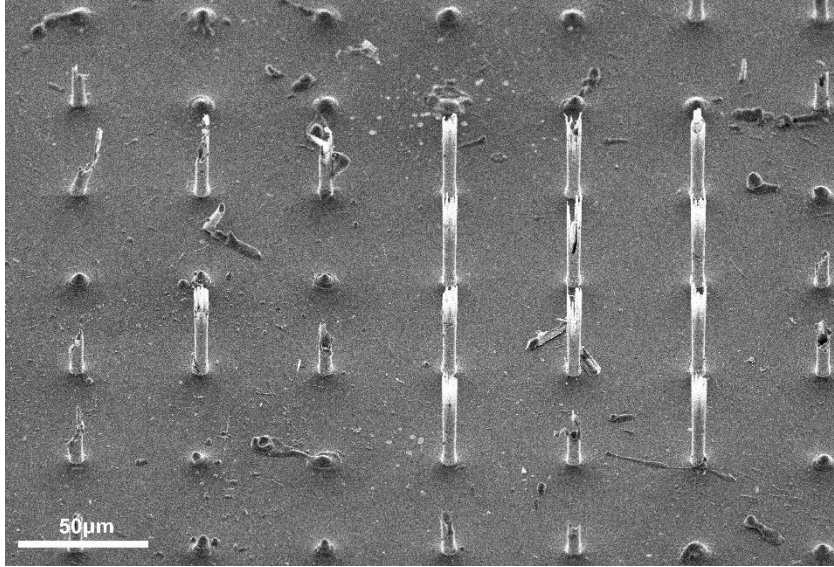
new geometry (high doping)



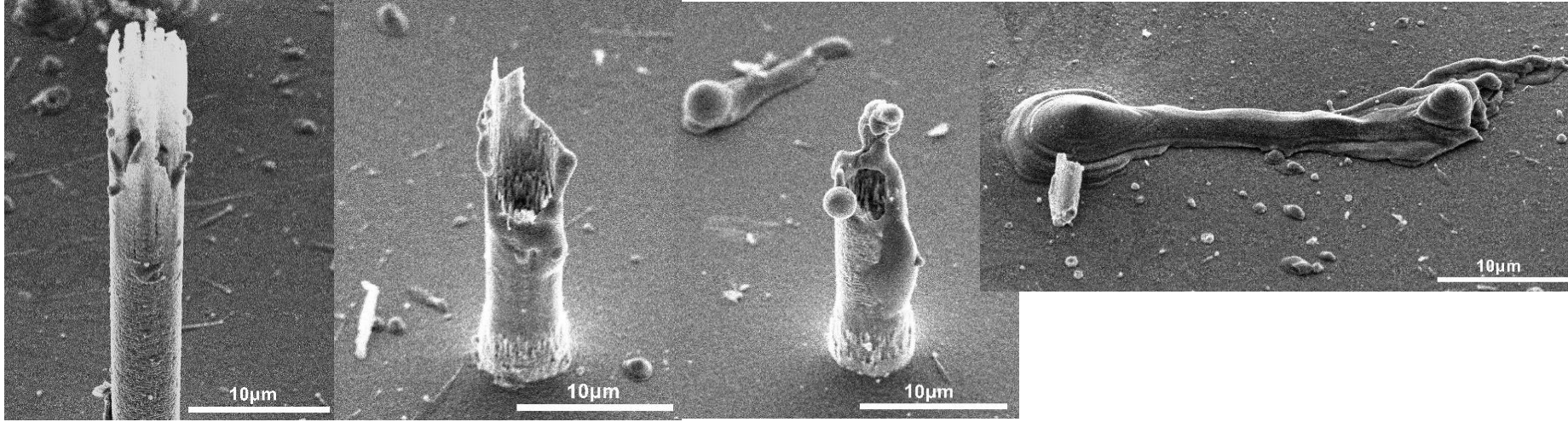
new geometry (low doping)



- Both samples with high doping show strong degradation
- Degradation seems to be scattered homogeneously over the whole sample
- New geometry with low doping is almost unchanged (although having completed a 24h longtime measurement at 1kV extraction voltage)

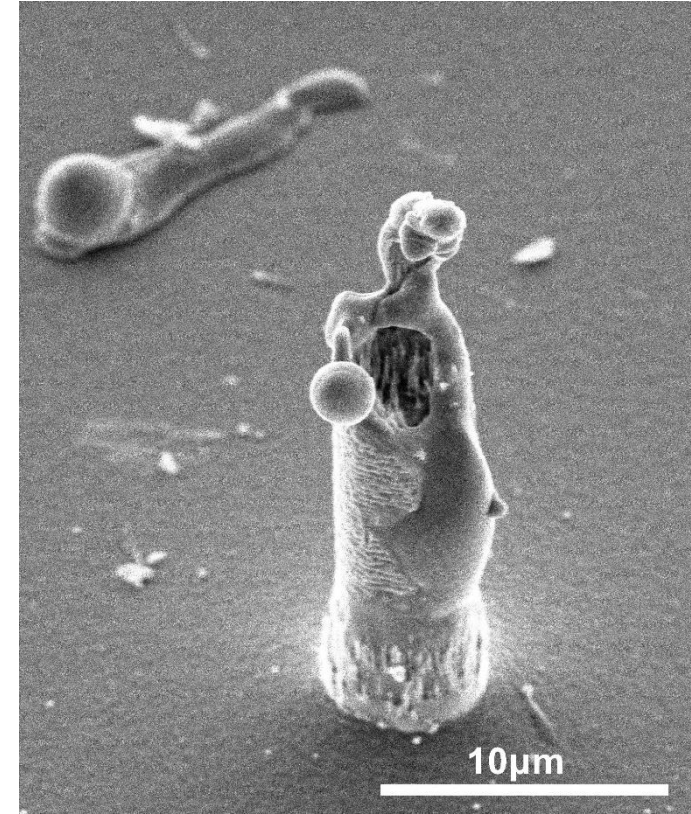


- SEM images after measurement show strong degradation for both low resistance silicon samples
- High resistance sample shows virtually no degradation in SEM images after measurements



- High magnification SEM images of destroyed emission tubes on the sample with new geometry and high doping concentration
- Failure mode in all cases seems to be melting due to high thermal stress

- New geometry shows lower onset voltage due to lower shielding due to thinned out structure and therefore higher field enhancement
- Presumed failure mode is high thermal stress while emitting
- Therefore sharper emitters are destroyed before blunter emitters start emitting
- Optimized material reduces thermal stress
- More emitters emit in parallel and increase achievable emission current
- Model calculations are being made to prove this theory



Any Questions?

